PRELIMINARY AMENDMENT

Continuation of U.S. Appln. No. 08/788,959 (Q76316)

IN THE CLAIMS:

Claims 1-20. (canceled)

21. (New) An ink jet recording head formed by a method comprising:

forming a first electrode layer on a diaphragm;

forming a piezoelectric layer on the first electrode layer;

forming a second electrode layer on the piezoelectric layer; and

etching completely through the second electrode layer, the piezoelectric layer, and the first electrode layer so that a portion of the diaphragm is exposed.

- 22. (New) The ink jet recording head according to claim 21, wherein the diaphragm is attached to a substrate.
- 23. (New) The ink jet recording head according to claim 22, wherein a nozzle plate is attached to the substrate.
- 24. (New) The ink jet recording head according to claim 23, wherein the nozzle plate is formed with a nozzle orifice.
- 25. (New) A method of manufacturing an ink jet recording head, the method comprising:

forming a first electrode layer on a diaphragm;

PRELIMINARY AMENDMENT

Continuation of U.S. Appln. No. 08/788,959 (Q76316)

forming a piezoelectric layer on the first electrode layer;

forming a second electrode layer on the piezoelectric layer; and

etching completely through the second electrode layer, the piezoelectric layer, and the first electrode layer so that a portion of the diaphragm is exposed.

- 26. (New) The method according to claim 25, further comprising attaching the diaphragm to a substrate.
- 27. (New) The method according to claim 26, further comprising attaching a nozzle plate to the substrate.
- 28. (New) The method according to claim 27, forming a nozzle orifice in the nozzle plate.
- 29. (New) The method according to claim 25, wherein only a single mask material is used to pattern the second electrode layer, the piezoelectric layer, and the first electrode layer during the etching step.
 - 30. (New) An ink jet recording head formed by a method comprising: forming a first electrode layer on a diaphragm; forming a piezoelectric layer on the first electrode layer;

• PRELIMINARY AMENDMENT Continuation of U.S. Appln. No. 08/788,959 (Q76316)

forming a second electrode layer on the piezoelectric layer; and etching completely through at least the second electrode layer and the piezoelectric layer so that a portion of the diaphragm is exposed.

- 31. (New) The ink jet recording head according to claim 30, wherein the diaphragm is attached to a substrate.
- 32. (New) The ink jet recording head according to claim 31, wherein a nozzle plate is attached to the substrate.
- 33. (New) The ink jet recording head according to claim 32, wherein the nozzle plate is formed with a nozzle orifice.